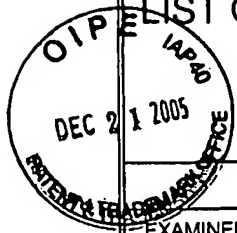


12/21/05



**LIST OF ART CITED BY APPLICANT**  
(PTO-1449)

ATTY. DOCKET NO. <b>ASU-0001</b>	APPLN. SERIAL NO. <b>10/626,880</b>
APPLICANT(S) <b>Susan D. ALLEN and Sergey I. KUDRYASHOV</b>	
FILING DATE <b>7/25/2003</b>	GROUP

**U.S. PATENT DOCUMENTS**

EXAMINER'S INITIALS	*PATENT NO.	*ISSUE DATE	*INVENTOR NAME	CLASS	SUBCLASS	FILING DATE
<i>MK</i>	4,720,621	10/19/04	Langen	134	1	7/23/01
	4,752,668	6/21/88	Rosenfield et al.	219	121	4/28/86
	5,023,424	6/11/91	Vaught	219	121.6	1/22/90
	5,151,135	9/29/92	Magee et al.	134	1	9/15/89
	5,332,879	7/26/94	Radhakrishnan et al.	219	121.69	12/2/92
	5,373,806	12/20/94	Logar	117	106	3/14/94
	5,516,369	5/14/96	Lur et al.	134	1.3	5/6/94
	5,531,857	7/2/96	Engelsberg et al.	156	345	9/15/94
	5,531,862	7/2/96	Otsubo et al.	156	643.1	7/19/94
	5,637,245	6/10/97	Shelton et al.	219	121.85	4/13/95
	5,643,472	7/1/97	Engelsberg et al.	216	65	9/19/94
	5,821,175	10/13/98	Engelsberg	438	795	11/9/94
	5,950,071	9/7/99	Hammond et al.	438	115	11/17/95
	5,958,268	9/28/99	Engelsberg et al.	219	121.84	3/1/96
	6,048,588	4/11/00	Engelsberg	427	554	3/16/98
	6,056,827	5/2/00	Fukui et al.	134	1	2/13/97
<i>MK</i>	6,064,035	5/16/00	Toller et al.	219	121.86	12/30/97

**U.S. PATENT APPLICATION PUBLICATIONS**

	*PATENT APPLN. PUB. NO.	*PUB. DATE	*APPLICANT	CLASS	SUBCLASS	
			<i>[Signature]</i>			

**U.S. PATENT APPLICATIONS**

	*APPLN. NO.	*FILING DATE	*INVENTOR	CLASS	SUBCLASS	
			<i>[Signature]</i>			

**FOREIGN PATENT DOCUMENTS**

EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						Yes	No
			<i>[Signature]</i>				

**LIST OF PRIOR ART CITED BY APPLICANT**  
(PTO-1449)

**OTHER ART (Including Author, Title, Date, Pertinent Pages, Publisher, Place of Publication, Etc.)**


<i>MK A</i>	"Laser cleaning of silicon surface with deposition of different liquid films", Y.F. Lu, et al., Applied Surface Science 138-139 (1999) 140-144
<i>B</i>	"Optical and Acoustic Study of Nucleation and Growth of Bubbles at a Liquid-Solid Interface Induced by Nanosecond-Pulsed-Laser Heating", O. Yavas, et al., Applied Physics A 58, 407-415(1994)
<i>C</i>	"Laser Cleaning of Silicon Wafers: Mechanisms and Efficiencies", M. Mosbacher, et al., Second International Symposium on Laser Precision Microfabrication(2002)
<i>MK D</i>	"Phase Separation in Fluid Systems by Spinodal Decomposition: A Molecular-Dynamics Simulation", Farid F. Abraham, et al., Physical Review Letters, Volume 36, Number 5, 2 February 1976
<del>E</del>	<del>"Physicochemical and Engineering Fundamentals and Applications", Sjoerd van Stralen, et al.</del>

<del>MK F</del>	"CRC Handbook of Chemistry and Physics", David R. Lide, Ph.D., Handbook of Chemistry and Physics, CRC Press LLC, 79 <sup>th</sup> Edition 1998-1999
<del>MKG</del>	"Cavitation and tension in liquids.", Matsumoto Y., et al., IOP Publishing Ltd., 1987
<del>H</del>	<del>"Methods for Surface Particle Removal: A Comparative Study", Juan Bardina</del>
<del>T</del>	<del>"Explosive Shocks in Air", Gilbert Ford Kinney, The Macmillan Company, New York</del>
<del>J</del>	<del>"Laser-assisted particle removal from silicon surfaces", S.J. Lee, et al., Center for Laser Science and Engineering, The University of Iowa, Iowa City, IA 52242, USA</del>
MKK	"Dynamic Particle Removal by Nanosecond Dry Laser Cleaning: Theory", N. Arnold, et al., International Symposium on Laser Precision Microfabrication (2002)
MKL	"Laser assisted particle removal from silicon wafers", M. Mosbacher, et al., Particles on Surfaces 7: Detection, Adhesion and Removal, pp. 275-293 Ed. K.L. Mittal © VSP 2002
<del>M</del>	<del>"Encyclopedia of Physics", Rita G. Lerner, et al., VCH Publishers, Inc.</del>
<del>N</del>	<del>"Boundary of Thermodynamic Stability", Gordon and Breach Science Publishers</del>
<del>O</del>	<del>"Physical Chemistry of Surfaces", Arthur W. Adamson, Fifth Edition, A Wiley-Interscience Publication, John Wiley &amp; Sons, Inc.</del>
MKP	"Physisorption of Cyclohexane on a SiO <sub>2</sub> /Si Substrate: Evidence of a Wetting Transition above the Triple Point", Wolfgang H. Lawnik, et al., Langmuir 1995, 11, 3075-3082
Q	<del>"The Homogeneous Nucleation Limits of Liquids", C.T. Avedisian, Sibley School of Mechanical and Aerospace Engineering, Cornell University, Ithaca, New York 14853</del>
MKR	"Adhesion between Nanoscale Rough Surfaces", Yakov I. Rabinovich, et al., Journal of Colloid and Interface Science 232, 17-24 (2000)
MKS	"Optical probing of the temperature transients during pulsed-laser induced boiling of liquids", Hee K. Park, et al., © 1996 American Institute of Physics. [S0003-6951(96)04805-X]
MKT	"Pressure generation and measurement in the rapid vaporization of water on a pulsed-laser-heated surface", Hee K. Park, et al., © 1996 American Institute of Physics. [S0021-8979(96)04618-X]
MKU	"Advances in Colloid and Interface Science", H. Krupp, Volume 1 No. 2 May 1967
MKV	"Explosive Boiling of Water Films Adjacent to Heated Surfaces: A Microscopic Description", Yusheng Dou, et al., J. Phys. Chem. A 2001, 105, 2748-2755
MKW	"Thickness effects of water overlayer on its explosive evaporation at heated metal surfaces", Yusheng Dou, et al., Nuclear Instruments and Method in Physics Research B 180 (2001) 105-111
MKX	"Infrared laser-induced desorption of H <sub>2</sub> O and hydrocarbons from optical surfaces", Susan D. Allen, et al., Appl. Phys. Lett. 41(5), 1 September 1982
MKY	"Contaminant and defect analysis of optical surfaces by infrared laser induced desorption", S.D. Allen, et al., Appl. Phys. Lett. 45(9), 1 November 1984
MKZ	"Defect characteristics of optical surfaces using pulsed laser damage methods", J.O. Porteus, et al., Optical Engineering /October 1986, Vol. 25 No. 10/ 1171
MKAA	"Laser-assisted micron scale particle removal", K. Imen and S.D. Allen, Appl. Phys. Lett. 58(2), 14 January 1991
MKBB	"Efficient pulsed laser removal of 0.2 µm sized particles from a solid surface", W. Zapka and W. Ziemlich, App. Phys. Lett. 58(20), 20 May 1991
MKCC	"CO <sub>2</sub> laser assisted particle removal threshold measurements", S.J. Lee, et al., Appl. Phys. Lett. 61(19), 9 November 1992
MKDD	"Removal of small particles from surfaces by pulsed laser irradiation: observations and a mechanism", J.D. Kelley, et al., SPIE Vol. 1415 Modeling and Simulation of Laser Systems II (1991)/211
MKEE	"Laser-cleaning techniques for removal of surface particulates", Andrew C. Tam, et al., J. Appl. Phys. 71(7), 1 April 1992
MKEF	"Bubble nucleation and pressure generation during laser cleaning of surfaces", O. Yavas, et al., Appl. Phys. A 64, 331-339 (1997)
MKGG	"Universal threshold for the steam laser cleaning of submicron spherical particles from silicon", M. Mosbacher, et al., Appl. Phys. A 70, 669-672 (2000)

Serial No.: 10/626,880

Docket No.: ASU-0001

SHEET 3 OF 3

HH MK	"Optical Reflectance and Scattering Studies of Nucleation and Growth of Bubbles at a Liquid-Solid Interface Induced by Pulsed Laser Heating", Oguz Yavas and Paul Leiderer, Vo. 70, Number 12, Physical Review Letters, 22 March 1993
II MK	"The modeling of excimer laser particle removal from hydrophilic silicon surfaces", X. Wu, et al., Journal of Applied Physics, Vo. 87, Number 8, 15 April 2000 © 2000 American Institute of Physics
JJ MK	"Modeling laser-assisted particle removal using molecular dynamics", K.M. Smith, et al., Appl. Phys. A 00, 1-6 (2003)
KK	<del>"Blustered Ensemble Averaging: A Techniques for Visualizing Qualitative Features of Stochastic Simulations", Kayne M. Smith, et al.</del>
LL MK	Grigor'ev et al, Physical Quantities, Energoatomizdat, Moscow (1991)
EXAMINER	DATE CONSIDERED
	04/29/07

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.

04/28/2004

SHEET 1 OF 1

<b>LIST OF PRIOR ART CITED BY APPLICANT</b> (PTO-1449)				ATTY. DOCKET NO. <b>ASU-0001</b>		APPLN. SERIAL NO. <b>10/626,880</b>	
				APPLICANT(S) <b>Susan D. ALLEN and Sergey I. KUDRYASHOV</b>			
				CUSTOMER NO. 34610			
				FILING DATE <b>July 25, 2003</b>		GROUP	

PATENT & TRADEMARK OFFICE  
 APR 28 2004

U.S. PATENT DOCUMENTS						
EXAMINER'S INITIALS	*PATENT NO.	*ISSUE DATE	*INVENTOR NAME	CLASS	SUBCLASS	FILING DATE
MK	4,987,286	1/22/1991	ALLEN			
/	5,024,968	6/18/1991	ENGELSBURG			
/	5,669,979	9/23/1997	ELLIOTT et al.			
/	5,800,625	9/1/1998	ENGELSBURG et al.			
MK	6,066,032	5/23/2000	BORDEN et al.			

U.S. PATENT APPLICATION PUBLICATIONS					
*PATENT APPLN. PUB. NO.	*PUB. DATE	*APPLICANT	CLASS	SUBCLASS	

U.S. PATENT APPLICATIONS					
*APPLN. NO.	*FILING DATE	*INVENTOR	CLASS	SUBCLASS	

FOREIGN PATENT DOCUMENTS							
EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						Yes	No

OTHER ART (Including Author, Title, Date, Pertinent Pages, Publisher, Place of Publication, Etc.)	

EXAMINER <i>[Signature]</i>	DATE CONSIDERED <b>04/27/07</b>
-----------------------------	---------------------------------

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.